# Surface Technology & Materials Science



# Software Development with VBA for Carl Zeiss AxioVision 4.x **Customized Applications in Quantitative Microstructure Analysis**

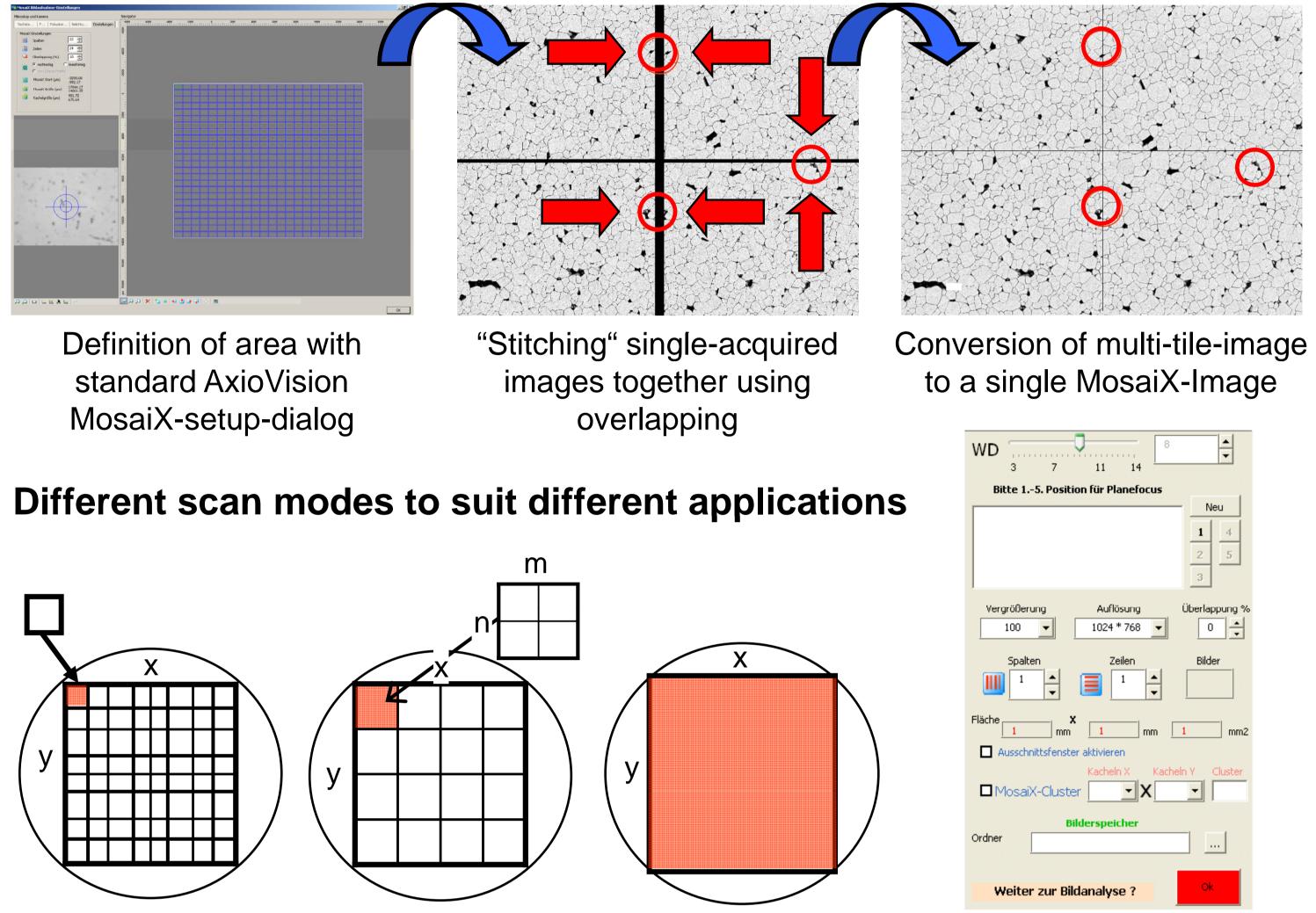
# **Demands in state-of-the-art QMA meet AxioVision**

Automated image acquisition – Cluster Acquisition

New requirements for classic QMA due to ongoing material engineering and increasing standards in quality assurance demand

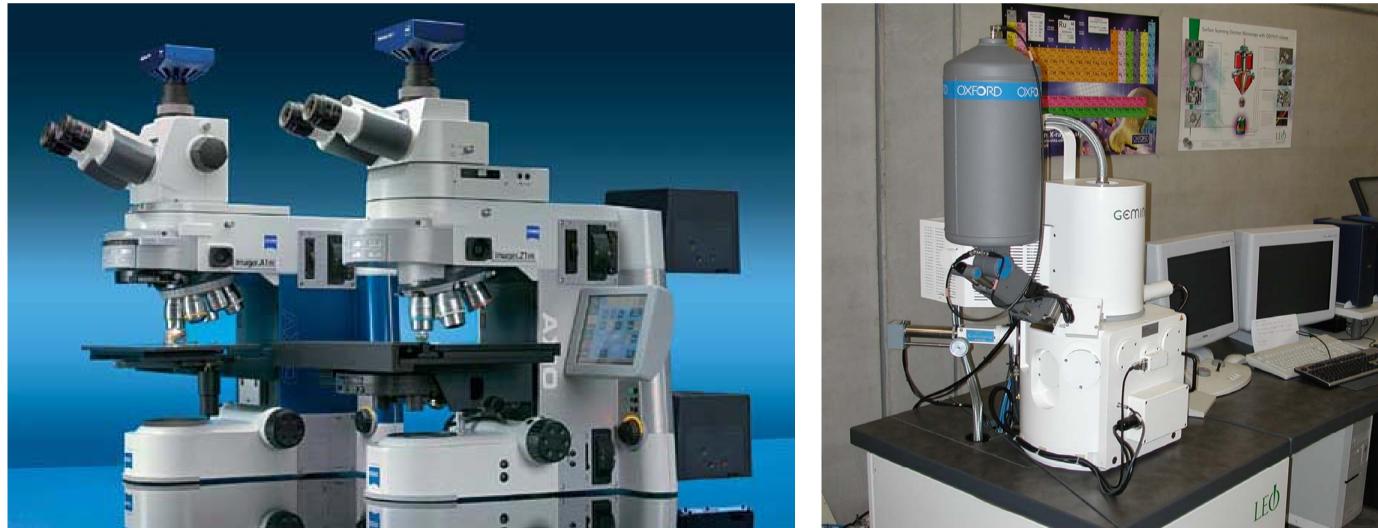
- Fast and reliable image acquisition
- → Increasing scan-areas with upscaling to entire parts
- Increasing magnification up to resolution-limits
- → Reliable focus over large areas at high magnification

**Processing large areas with AxioVision MosaiX-feature** 

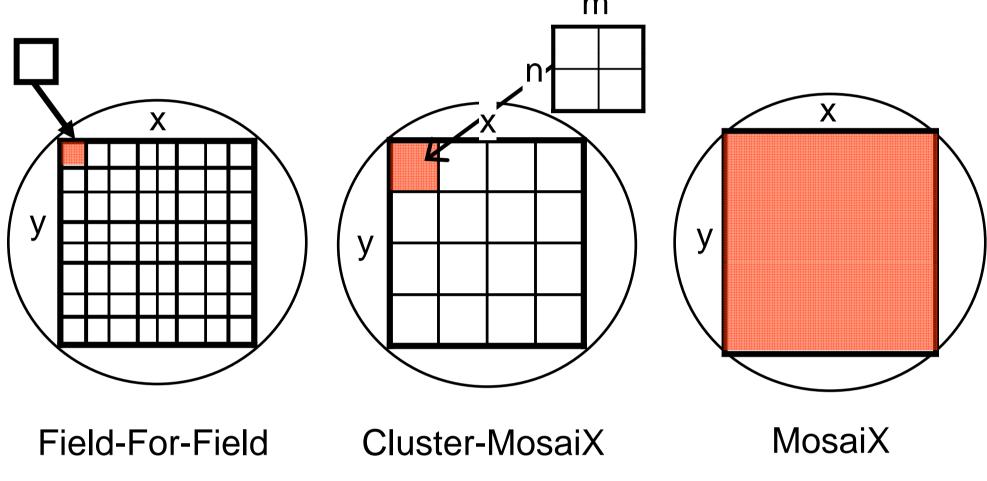


- Complex detection/measurement in advanced image analysis
- User friendly applications QMA for non-highly-trained personnel
- High transparency for control of processes
- → Easy data management
- → Tailored reporting

AxioVision 4 is an extensive software platform able to fulfill these requirements. Its functionality covers control of Carl Zeiss light microscopes and cameras and provides a wide range of image analysis. AV4 can be programmed via VBA to generate customized applications to create automated solutions even for the most sophisticated problems in materials microscopy. Basically designed for light microscopy it also has been possible to create an interface for a LEO Gemini SEM to be operated via an AxioVision 4 VBA project.







Interface for scan modes at LEO Gemini SEM

# Automated image acquisition – Multifocus

### Challenge: multi-sample-scanning (approx. 70000 µm x 35000 µm)

Two Carl Zeiss Axiolmager (light-) Microscopes for Material Microscopy

LEO Gemini Scanning Electron Microscope at HTW-Aalen

# Taking the next step – solutions with AxioVision

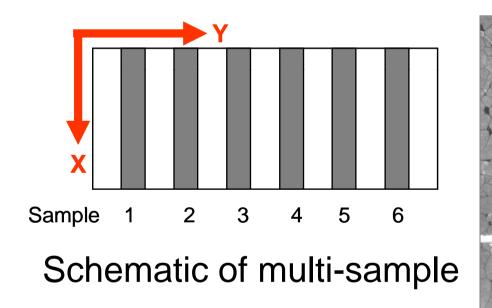
## Automated image acquisition

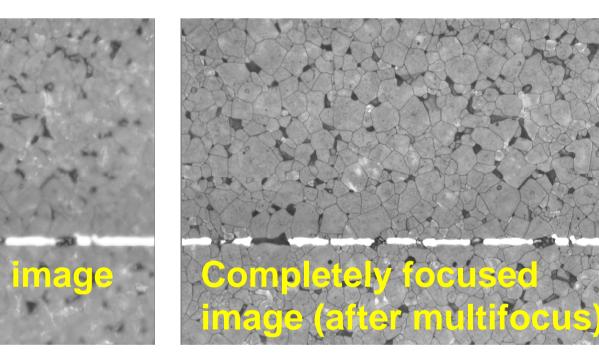
Module Module Module **Cluster Acquisition Multifocus** processing of large reliable focus, high magnifications areas

**Intelligent Acquisition** acquisition of large areas, smart mode, batch mode

 $\rightarrow$  Topographic unevenness minimum 4 µm

- $\rightarrow$  Deviation in level ca. 200 µm (entire multisample)
- $\rightarrow$  Focus depth at 500x magnification: approx. 0.54 µm
- $\rightarrow$  Topographic unevenness within single measure-field: >> 0.54 µm





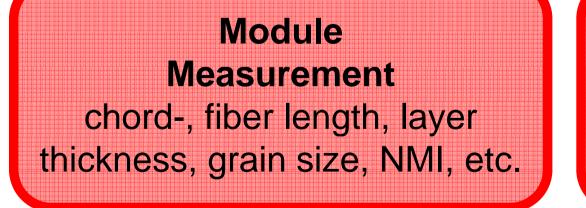
Solution: combination of all focus functions in AV  $\rightarrow$  "Multifocus" + automated image-acquisition of multi-sample  $\rightarrow$  "Batchmode"

# Image analysis, measurement and visualization

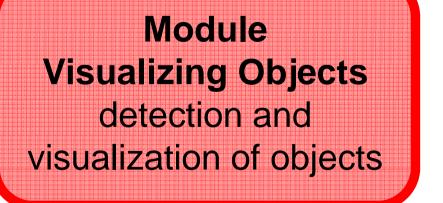
### Image analysis, measurement and visualization

Module **Image Processing** menu based and automated

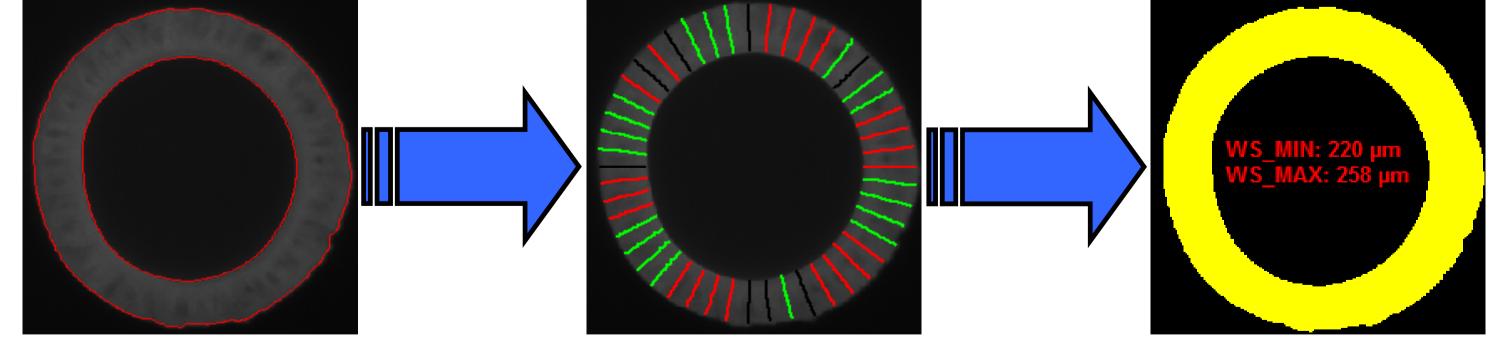
#### Data processing

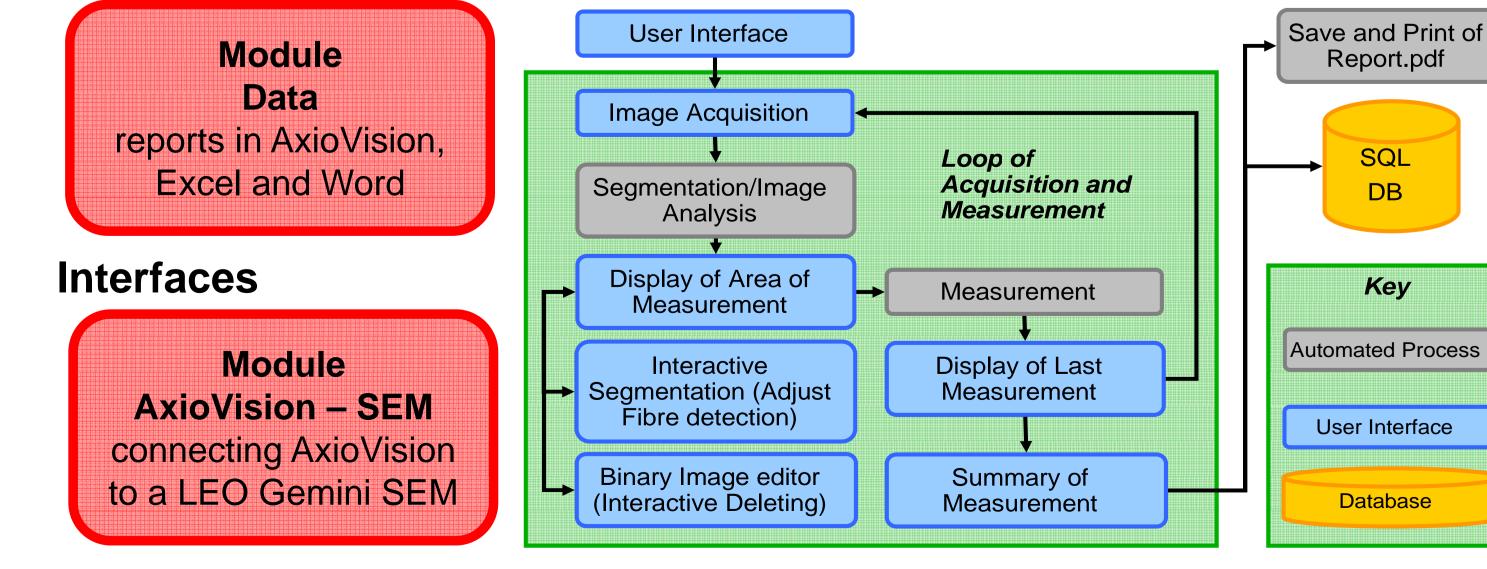


## Work flow of an application



# Using chords to determine layer thickness



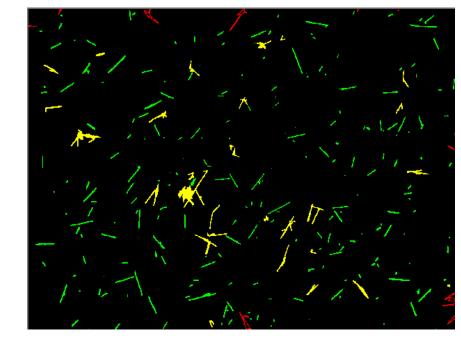


High modularity allows efficient development of customized applications

Detecting object

Fitting chords and measuring length

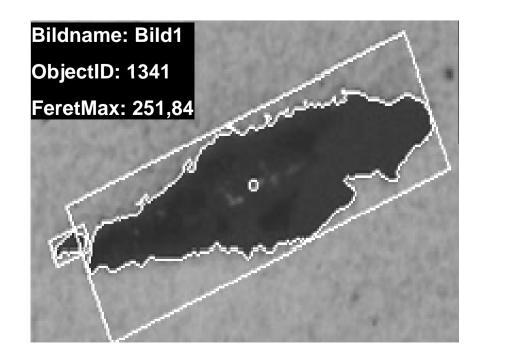
### Examples for detection and visualization



**Classification of fibers** via different colors

**Reconstruction of** ceramic grains

Display measured area and results



Visualization of defects in ceramics

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